

# SUBSTRATE CLEANING SYSTEM

## MODEL SCSx128

### **DESCRIPTION:**

The highly efficient Model SCSx128 is the ideal solution for submicron cleaning of Photomasks, Wafers and Substrates. The very reliable and cost effective system utilizes proven assortment of cleaning technologies. The SCSx128 can be configured with several different cleaning options from Atomizing Mist Nozzle, Brushes and Nozzles with Surfactant and/or DI-H<sub>2</sub>O; Megasonic Nozzle with DI-H<sub>2</sub>O or Surfactant for sub-micron and fine feature cleaning.

### **FEATURES:**

- Up to Twelve (12) Inch Diameter Substrate and 9" x 9" Photomask Compatibility.
- System Dimensions: 28" wide x 24" deep
- All components service accessible from front of system
- Main Spindle Assembly having DC Brushless Motor
- Adjustable Arm Speed and Travel Positions.
- Radially Exhausted Chamber for Maximum Laminar Flow. Microprocessor Control Capable of Retaining Thirty (30) Recipes having thirty (30) Steps each in Memory. Both number of Recipes & Steps are expandable upon request.
- Built in Safety Interlocks.
- Push Button Lid Open/Close.
- Touch Screen Graphic User Interface (GUI) with Ease of Programming & Security Lockouts with On-Screen Error Reporting.
- Maximum Capability of Two Arms
- Designed to SEMI S2/S8 Guidelines



**Example of Process Arms**



**System Cabinet**

### **OPTIONS:**

- Ability to integrate with Equipment Front End Module (EFM) for Automation purposes
- Various sizes of vacuum and edge-grip chucks for Wafers, Photomasks, and other Substrates
- Servo Spindle Motor for precise control & indexing.
- Height Adjustable Self-Cleaning Brush Assembly
- N<sub>2</sub> Drying Assist with 0.02  $\mu$ m Filtration
- Fixed or Oscillating Low Pressure Dispenses
- Surfactant or Photoresist Dispense Canister
- Auto Chamber Rinse
- Controllable & Adjustable Chamber Exhaust Assembly
- Stand-alone Mixing System for Surfactant
- 0.2  $\mu$ m Filtration for Low Pressure Dispenses
- D.I. Water Heater and Dispenses for Clean & Dry Assist.
- Oscillating Megasonic DI Water Dispense Arm
- Secondary Containment with Leak Detection
- CE Certification

